

**Amendments to the Specification:**

Please amend the specification, without prejudice, as follows, where underlining identifies added material and strikethroughs identify deleted material:

Amendment to first paragraph of page 1 (lines 1-4):

**CROSS-REFERENCE TO RELATED APPLICATIONS**

The present application is based upon and claims priority from International Application No. PCT/US03/27143, filed August 27, 2003, and entitled “A Hybrid Beam Deposition System and Methods for Fabricating Metal Oxide-ZnO Films, P-Type ZnO Films, and ZnO-Based II-VI Compound Semiconductor Devices.” and U.S. provisional patent application Serial No. 60/406,500, filed ~~28~~ August 28, 2002, entitled “Hybrid Beam Deposition System And Method For Fabricating Metal Oxide ZnO Films, P-Type ZnO Films, And ZnO-Based II-VI Group Compound Semiconductor Devices”.